

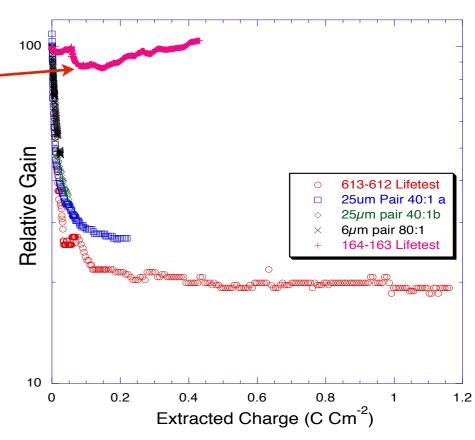
# Status, Requirements, and Plans for Baking & Scrubbing

Bob Wagner and Dean Walters LAPPD Single Tile Facility Review Friday 16 March 2012



### Status for Baking & Scrubbing

- No development or testing in progress at Argonne presently for baking or scrubbing
- Scrubbing:
  - Pre-conditioning test at SSL looks promising for minimal scrubbing
  - Performed on 33mm MCP pair 20µm pore with electrode over ALD
  - Bake at 350°C before scrub
  - Scrub current incremented  $1\mu A \rightarrow 2\mu A \rightarrow 3\mu A$
  - No drop in relative gain throughout



Scrub @ 3 x 10<sup>5</sup> gain, 700v per MCP



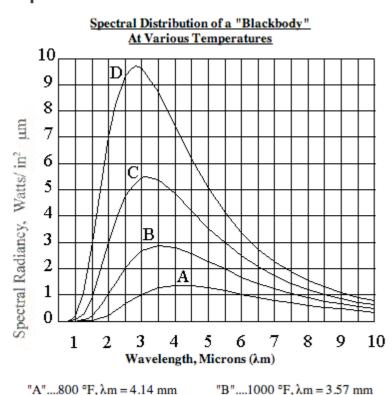
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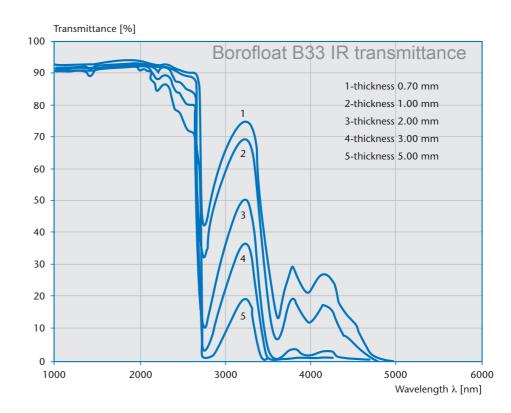
# Requirements for Baking

- ▶ Single Tile Processing System will operate at base pressure of ~10<sup>-9</sup> torr
- Assembled vacuum transfer chambers will be baked at 200-250°C
  - External heating tapes and Al foil wrap
  - · Internal halogen lamp heater assemblies in 3 of the 4 work areas
  - Initial bakeout will be 1-2 months to achieve base pressure
- Bakeout of single tile assembly parts is done at 350°C locally using halogen lamp heater assemblies
  - · Assume radiant heating, e.g. T3 halogen lamp

"D"....1400 °F,  $\lambda m = 2.81 \text{ mm}$ 

 If necessary, use conduction heating via metal plate heated by T3 halogen lamp





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"C"....1200 °F,  $\lambda m = 3.14$  mm

### Requirements for Scrubbing

- Depending on coatings & pre-baking, SSL has seen behavior consistent with no gain drop during for several  $\times$  0.1 C/cm2
- Whether gain changes or not, assume some scrubbing is wanted to precondition MCPs, e.g. remove residual trapped gas
  - Any changes in chemistry? SSL behavior seems to imply no.
- Scrub with UV Pen-Ray lamp?
  - Mercury (primary energy at 254nm)?

#### Lamps available in variety of shapes for a price







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# Plans for Baking & Scrubbing

- Baking -- Internal
  - · Halogen lamp heater arrays part of Vacuum Transfer System design
  - Quotes in cost book for heater arrays and controllers
  - Baking stations in
    - Top window load-lock station
    - Photocathode deposition (for alkali metal deposition)
    - Tile Base Scrub Station
- Baking -- External
  - Initial longterm bake with heater tapes and foil for achieving base pressure target
  - Periodic rebaking as required to maintain base pressure, recover after syste, modifications, remove accumulated or unexpected contaminants
- Scrubbing
  - · Take advantage of the experience and knowledge of Ossy and Jason at SSL
  - The mechanism of scrubbing needs study (in papers and in the lab) as we put the system together

